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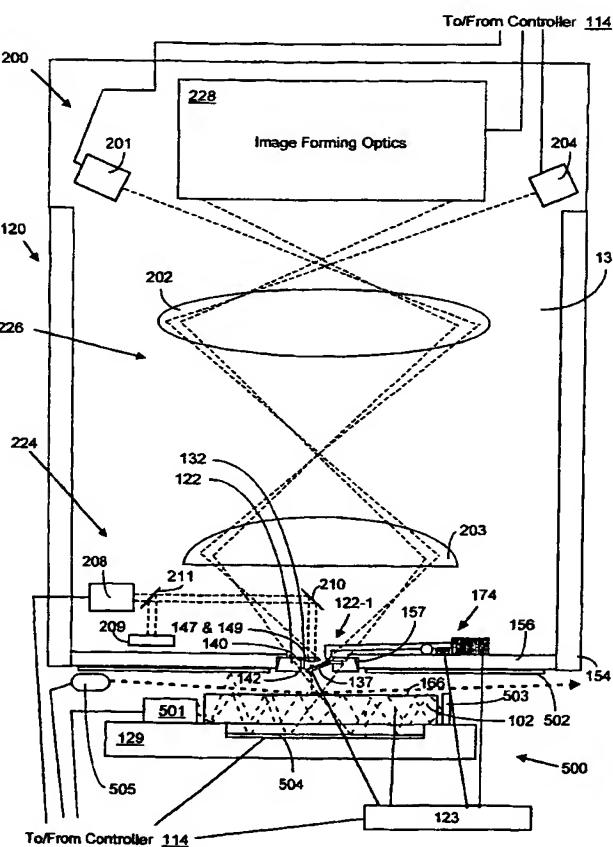
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**(54) Title: OBJECT INSPECTION AND/OR MODIFICATION SYSTEM AND METHOD**

(57) **Abstract:** A scanning probe microscope system (100) includes an objective lens (147), a clamping circuit (404), a tip deflection measurement circuit (421), a cantilever (136), and a probe (137) for modifying and inspecting an object (102) disposed on a stage (129).



WO 01/03157 A1